

In re PATENT APPLICATION of

Shunji Hayashi

Attorney Docket No. SKI.008C2

Date: October 12, 2005

Serial No.: 10/712,100

Examiner: K. Bahta

Filed: November 14, 2003

Art Unit No.: 2125

For:

METHOD AND SYSTEM FOR MANAGING SEMICONDUCTOR

MANUFACTURING EQUIPMENT

LETTER OF RELATED APPLICATION

U.S. Patent and Trademark and Trademark Office Customer Window, Mail Stop Randolph Building 401 Dulany Street Alexandria, VA 22314

Sir:

The Examiner is hereby advised of co-pending U.S. Application Serial No. 11/061,813. The subject matter contained in this co-pending U.S. Application Serial No. 11/061,813 is related to the present application and thus may be material to the prosecution of this instant application.

This application is not to be construed as prior art. By bringing this application to the attention of the Examiner, Applicant does NOT waive the confidentiality provisions of 35 U.S.C. 122.

Respectfully submitted,

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